Atomic-Scale Nanoelectronics



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Molecular Nanoelectronics on Silicon?

Projected timeline for the electronics industry:

A. C. Seabaugh, P. Mazumder, *Proceedings of the IEEE*, <u>87</u>, 535 (1999).

1975	200	0 20	25 2	050	20	75	2100
СМС	os –	nanoscale CMOS					
tunnel SRAM							
		<u> </u>					
III-V RTD / transistor							
		single electronics					
Flash single electron memory							
					Mo Elec	lecul	ar cs

What can we do today?

Outline



Study silicon-based molecular nanotechnology issues with the UHV-STM

- Bottom-up approach in a pristine environment
- Studies on silicon bridge the gap between fundamental research and modern technology

Outline:

- (1) Robustness of Si(100)-2×1:H surface
- (2) STM-induced desorption: Implications for nanofab and CMOS
- (3) FCL: Single molecule studies (Organic and biological molecules)
- (4) Hybrid nanoelectronics and conventional microelectronics

Equipment / Facilities



- ThermoMicroscopes CP Research ® atomic force microscope (AFM)
- Room temperature ultra-high vacuum (UHV) scanning tunneling microscope (STM) interfaced to controlled atmosphere glove box
- Cryogenic UHV STM with variable temperature control between 10 K and 400 K.



Robustness of Si(100)-2×1:H

M. C. Hersam, D. S. Thompson, N. P. Guisinger, J. S. Moore, and J. W. Lyding, Appl. Phys. Lett., 78, 886 (2001).



XPS results after ambient exposure



Nanolithography on H Passivated Si(100)

J. W. Lyding, T.-C. Shen, J. S. Hubacek, J. R. Tucker, and G. C. Abeln, Appl. Phys. Lett., <u>64</u>, 2010 (1994).



A relatively stable and unreactive surface is produced by hydrogen passivating the Si(100)-2×1 surface in ultra-high vacuum (UHV).



Highly reactive "dangling bonds" are created by using the STM as a highly localized electron beam.



The linewidth and desorption yield are a function of the incident electron energy, the current density, and the total electron dose.

- Selective chemistry can be accomplished on patterned areas.
- Large isotope effect exists between hydrogen and deuterium.

CMOS \leftrightarrow **STM Analogy**



Conventional Silicon Microelectronics



Electron Stimulated Desorption Isotope Effect

Ph. Avouris, R. E. Walkup, A. R. Rossi, T.-C. Shen, G. C. Abeln, J. R. Tucker, and J. W. Lyding, Chem. Phys. Lett., 257, 148 (1996).



- Deuterium has a much lower ESD yield than hydrogen.
- Desorption conditions exist where all of the hydrogen and none of the deuterium is removed from the surface.
- Deuterating CMOS devices leads to longer device lifetimes.

Direct Measurement of D:H Ratio

M. C. Hersam, K. Cheng, N. P. Guisinger, J. Lee, and J. W. Lyding, submitted to Appl. Phys. Lett. (2001).



Passivation at 650 K \Rightarrow D:H Ratio ~ 5 Passivation at 350 K \Rightarrow D:H Ratio ~ 50



Statistical thermodynamics model confirms experimental results.

Silicon-Based Molecular Nanoelectronics

Goal: Single Molecule Electronic Switching and Storage Conformational or Electronic State Transitions

Approach: Bottom-Up UHV STM -> Atomic Resolution

Hydrogen Resist Technique, Selective Molecular Adsorption Feedback Controlled Lithography Single Molecule Studies (NBE, CuPc & C_{60}) Nanoscale Contacting Scheme

New Directions

New Molecules, Nanobioelectronics, Nanochemical Analysis

Selective Oxidation

UHV Oxidation @ 10⁻⁶ Torr

J. W. Lyding, T.-C. Shen, J. S. Hubacek, J. R. Tucker, and G. C. Abeln, *Appl. Phys. Lett.*, <u>64</u>, 2010 (1994).

Loadlock Oxidation @ 4 psi



T.-C. Shen, C. Wang, J. W. Lyding, and J. R. Tucker, *Appl. Phys. Lett.*, <u>66</u>, 976 (1995).

Selective Nitridation

J. W. Lyding, T.-C. Shen, G. C. Abeln, C. Wang, and J. R. Tucker, *Nanotechnology*, 7, 128 (1996).



Selective Metallization: Physical Deposition



T.-C. Shen, C. Wang, and J. R. Tucker, *Phys. Rev. Lett.* <u>78</u>, 1271 (1997).



T. Hashizume, S. Heike, M. I. Lutwyche, S. Watanabe, K. Nakajima, T. Nishi and Y. Wada, *Jpn. J. Appl. Phys*, <u>35</u>(8B), Part 2, L1085-L1088 (1996).

Selective Metallization: CVD of Gold

IBM Collaborators: Phaedon Avouris and Paul Seidler

Selective Au depostion:

1. Room T Dose: Incomplete Dissociation 2. High T Dose: Metal Deposition

After 10L Dose After 10L Dose After 20L Dose







Precursor Molecule: CH₃CH₂AuP(CH₃)₃

Selective Metallization: CVD of Aluminum

Novel amine-stabilized alane Al precursor developed by Dr. Hyungsoo Choi, Beckman Institute



- To improve morphology for thicker layers, use TiCl₄ as a nucleating agent.
- Selective depositon of TiCl₄ has been demonstrated at room temperature.

Selective Molecular Adsorption of Norbornadiene on Silicon

G. C. Abeln, M. C. Hersam, D. S. Thompson, S.-T. Hwang, H. Choi, J. S. Moore, and J. W. Lyding, J. Vac. Sci. Technol. B, 16, 3874 (1998).



Norbornadiene (NBE) is conformationally predisposed to react with adjacent Si(100) dimers to form organosilicon "cage" structures ([2+2] cycloaddition reaction).

Silicon-Based Molecular Nanoelectronics A Bottom-Up Approach



Silicon-Based Molecular Nanoelectronics A Bottom-Up Approach



Copper Phthalocyanine Stationary vs Rotating Molecules



Evidence of Molecular Rotation



Individual NBE Molecules on Si(100)







(45 Å)² filled states image of four depassivated sites

Filled states image after norbornadiene dose

Empty states image after norbornadiene dose

- STM images are a convolution of topography and electronic structure.
- Multi-bias imaging can sometimes distinguish different adsorbed molecules.
- In this case, the boxed molecule behaves like water, whereas the circled molecule is presumably norbornadiene (NBE).

STM spectroscopy can provide deconvolved information about electronic structure.

Copper Phthalocyanine - Spectroscopic Behavior



Copper Phthalocyanine – Tip Induced Motion



Single Molecule Spectroscopy C₆₀ - A Case Study



Intramolecular Spectroscopy of C_{60}



Use pattern recognition algorithm which analyzes 3D data set in energy space to identify electronically distinct regions.

Location/Registration of Nanostructures

M. C. Hersam, G. C. Abeln, and J. W. Lyding, *Microelectronic Engineering*, <u>47</u>, 235 (1999).



Delineation of a *p-n* junction after location.

STM Imaging of a p-n Junction



Electrically Contacting Nanostructures p-n Junction Approach

STM Nanofabrication Zone



p-n junction approach

- Compatible with UHV processing and H-passivation/depassivation schemes.
- Will enable potentiometry and spectroscopy for measuring nanoscale electronic structure.



Si(100), n-type, As-doped (< 0.005 Ω-cm)

Processing:

1.) Boron predep @ 950°C for 1 hour 2.) ~ 1270°C anneal in UHV for 1 min.



Image before patterning.

Image after patterning a line across the *p-n* junction.

Nanoscale Charge Transport Measurements

- Electrical breakdown measurements on nanoscale systems
 - Gold nanowires (nanoscale electromigration)
 - Carbon nanotubes (quantized breakdown)
 - > New molecules (e.g., DNA, thiol-derived SAMs)
 - > Novel reliability techniques may be needed

Gold Nanowire Failure:



Nanotube breakdown:



M. C. Hersam, et al., Appl. Phys. Lett., 72, 915 (1998).

Nanotube breakdown data is from: M. C. Hersam, et al., *Science and Application of Nanotubes*, editors: Tománek and Richard Enbody, Kluwer Academic Publishers, p. 223 (2000).

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